L Number	Hits	Search Text	DB	Time stamp
1	132	700/99-103,121;702/177,184.ccls. and	USPAT;	2004/10/25 17:17
		@pd>=20040714	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
2	41	(700/99-103,121;702/177,184.ccls. and	USPAT;	2004/10/25 17:30
2	**			2004/10/25 17:30
		@pd>=20040714) and maintenance	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
3	25	(700/99-103,121;702/177,184.ccls. and	USPAT;	2004/10/25 17:35
	ļ	@pd>=20040714) and maintenance and schedul\$6	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
4	38	maintenance same schedul\$6 same gap	USPAT;	2004/10/25 18:08
		, J. <u>.</u>	US-PGPUB;	= 000, 20, 20
		•	EPO; JPO;	
			DERWENT;	1
			•	
-	140	(maintenance near cohedules) with (decretion)	IBM_TDB	2004/10/05 10 55
5	149	(maintenance near schedul\$6) with (downtime	USPAT;	2004/10/25 18:09
		or down-time or "down time" or gap)	US-PGPUB;	
1			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
6	2	(maintenance near schedul\$6) with (gap)	USPAT;	2004/10/25 18:11
			US-PGPUB;	
			EPO; JPO;	
1			DERWENT;	
			IBM TDB	
7	17	(maintenance near schedul\$6) with (space or	USPAT;	2004/10/25 18:11
'		spacing)	US-PGPUB;	2004/10/25 10:11
		apacing)	EPO; JPO;	
Í				
			DERWENT;	
		702/1041-	IBM_TDB	
-	204	702/184.ccls.	USPAT;	2004/07/13 12:59
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
<b> </b> -	100	702/177.ccls.	USPAT;	2004/07/13 13:09
			US-PGPUB;	
			EPO; JPO;	
İ			DERWENT;	
			IBM TDB	
-	320	700/100.ccls.	USPAT;	2004/07/13 13:09
			US-PGPUB;	, ,== ======
			EPO; JPO;	
		,	DERWENT;	ļ
•			IBM TDB	
_	90	700/100.ccls. and maintenance	USPAT;	2004/07/13 13:19
		100, 100. Colb. and maintenance	US-PGPUB;	2004/07/13 13:19
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	000440=45=
-	12	maintenance with schedul\$5 with gap	USPAT;	2004/07/13 13:23
			US-PGPUB;	
			EPO; JPO;	
.			DERWENT;	
			IBM_TDB	
-	564	maintenance near2 gap	USPAT;	2004/07/13 13:24
]			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
_	282	maintenance near gap	USPAT;	2004/07/13 13:24
	202	and	US-PGPUB;	2004/0//13 13:24
			EPO; JPO;	
			DERWENT;	
L			IBM_TDB_	

				1
-	0	(maintenance near gap) same schedul\$5	USPAT;	2004/07/13 13:24
			US-PGPUB;	į
]			EPO; JPO;	
			DERWENT;	
	_	/	IBM_TDB	
-	1	(maintenance near2 gap) same schedul\$5	USPAT;	2004/07/13 13:24
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
1			IBM_TDB	
-	289		USPAT;	2004/07/13 15:29
		downtime or "down time" or "down-time")	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	12	maintenance with schedul\$5 with (parallel)	USPAT;	2004/07/13 15:32
			US-PGPUB;	
			EPO; JPO;	
i			DERWENT;	
			IBM_TDB	
-	24	maintenance with schedul\$5 with	USPAT;	2004/07/13 16:00
		(simultaneous\$6)	US-PGPUB;	
			EPO; JPO;	
[			DERWENT;	
i	1		IBM_TDB	
-	67	(maintenance near (simultaneous\$6 or	USPAT;	2004/07/13 16:08
		parallel)) and (downstream or upstream)	US-PGPUB;	
		•	EPO; JPO;	
			DERWENT;	
	}		IBM TDB	
-	50	maintenance near (downstream or upstream)	USPAT;	2004/07/13 16:09
		( a a a a a a a a a a a a a a a a a a a	US-PGPUB;	2001,07,15 10.05
			EPO; JPO;	
			DERWENT;	
	1		IBM TDB	
_	131	maintenance with (downstream or upstream)	USPAT;	2004/07/13 16:12
		with (schedul\$5 or perform\$5)	US-PGPUB;	2004/07/15 10:12
		ween (sensually of policimys)	EPO; JPO;	
	•		DERWENT;	
			IBM TDB	
-	15175	maintenance near (schedul\$5 or perform\$5)	USPAT;	2004/07/13 16:47
		, and the policy of policy in the policy in	US-PGPUB;	2001, 07, 13 10.17
			EPO; JPO;	
			DERWENT;	
1	ļ		IBM TDB	
-	4	(maintenance near (schedul\$5 or perform\$5))	USPAT;	2004/07/13 16:21
	1	with line with (upstream or downstream)	US-PGPUB;	2007/07/13 16:21
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
-	75	(maintenance near (schedul\$5 or perform\$5))	USPAT;	2004/07/12 16:22
	, ,	same ("manufacturing line" or "production	US-PGPUB;	2004/07/13 16:23
		line" or "assembly line")	EPO; JPO;	
	1	TIME OF ABBUMDTA TIME /		
			DERWENT;	
_	32	(maintenance near (schodulče om nowformes))	IBM_TDB	2004/07/12 17 05
	32	<pre>(maintenance near (schedul\$5 or perform\$5)) with downstream</pre>	USPAT;	2004/07/13 17:03
		with downstream	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
_	401	maintananga naam timina	IBM_TDB	
-	401	maintenance near timing	USPAT;	2004/07/13 20:55
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
		(madmbanana mana kimita ) = 3	IBM_TDB	
<del>-</del>	10	(maintenance near timing) and	USPAT;	2004/07/13 20:58
		("manufacturing line" or "production line"	US-PGPUB;	
		or "assembly line")	EPO; JPO;	
			DERWENT;	
			IBM_TDB	

-	2	(maintenance near wait\$5) and	USPAT;	2004/07/13 20:59
		("manufacturing line" or "production line"	US-PGPUB;	
		or "assembly line")	EPO; JPO;	
			DERWENT;	
_	215	700/121.ccls. and maintenance	USPAT;	2004/07/13 20:59
		, vo, 111 octo. and maintenance	US-PGPUB;	2004/07/13 20.39
1			EPO; JPO;	
			DERWENT;	
			IBM TDB	
-	38	700/121.ccls. and (maintenance with	USPAT;	2004/07/13 21:14
		schedul\$9)	US-PGPUB;	
			EPO; JPO;	1
			DERWENT;	
			IBM_TDB	
-	13	maintenance with schedul\$9 with idl\$6	USPAT;	2004/07/13 21:17
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
_	470	700/99,101-103.ccls.	IBM_TDB	2004/07/22 22 20
"	4.0	700/99,101-103.CC18.	USPAT;	2004/07/13 21:18
			US-PGPUB; EPO; JPO;	
	1		DERWENT;	]
			IBM TDB	
_	38	700/99,101-103.ccls. and (schedul\$5 with	USPAT;	2004/07/13 21:26
		maintenance)	US-PGPUB;	2001/01/13 21.20
			EPO; JPO;	
			DERWENT;	Į.
	i		IBM TDB	
-	30	maintenance with schedul\$9 with during with	USPAT;	2004/07/13 21:42
	:	(downtime or "down time" or "down-time")	US-PGPUB;	
			EPO; JPO;	İ
			DERWENT;	
		1017 177777	IBM_TDB	
_	691	ASML-NETHERLANDS-BV ASML-NETHERLANDS-B-V	USPAT;	2004/07/13 21:47
		"ASML-NETHERLANDS-B.V" ASML-NETHERLANDS-NV	US-PGPUB;	
		ASML-MASKTOOLS-NETHERLANDS-BV ASML-MASKTOOLS-NETHERLANDS-B-V	EPO; JPO;	
		"ASML-MASKTOOLS NETHERLANDS-B.V"	DERWENT; IBM TDB	
		ASML-MASKTOOLS-B-V "ASML-MASKTOOLS-B.V"	100-100	
		ASML-NETHERLANDS		
¦ <b>-</b>	28		USPAT;	2004/07/13 21:53
; [		"ASML-NETHERLANDS-B.V" ASML-NETHERLANDS-NV	US-PGPUB;	2001, 07, 13 21.33
		ASML-MASKTOOLS-NETHERLANDS-BV	EPO; JPO;	
,		ASML-MASKTOOLS-NETHERLANDS-B-V	DERWENT;	
		"ASML-MASKTOOLS-NETHERLANDS-B.V"	IBM_TDB	
		ASML-MASKTOOLS-B.V"		
	, ,	ASML-NETHERLANDS) and maintenance		
-	16		USPAT;	2004/07/13 21:55
,		schedul\$6	US-PGPUB;	
	ļ		EPO; JPO;	
			DERWENT; IBM TDB	
_	726	(semiconductor or wafer) and ((coater or	USPAT;	2004/07/13 21:57
ļ		developer or track) same maintenance)	US-PGPUB;	2007/07/13 21:57
		-E	EPO; JPO;	
ļ			DERWENT;	
			IBM TDB	
-	35	(semiconductor or wafer) and ((coater or	USPAT;	2004/07/13 22:05
ļ		developer or track) same maintenance same	US-PGPUB;	
ļ		schedul\$5)	EPO; JPO;	
ļ			DERWENT;	
ļ			IBM_TDB	
-	556	coater with developer	USPAT;	2004/07/13 22:05
ļ			US-PGPUB;	
			EPO; JPO;	,
			DERWENT;	j
			IBM_TDB	

_	5	coater with developer with maintenance	USPAT;	2004/07/13 22:09
			US-PGPUB;	
			EPO; JPO;	
			DERWENT; IBM TDB	
-	3	, the same services and the same services are same services and the same services and the same services are same services are same services and the same services are same s	USPAT;	2004/07/13 22:10
		same (expos\$5)	US-PGPUB; EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	5	coater same developer same maintenance same (stepper or expos\$5 or photolithography)	USPAT; US-PGPUB;	2004/07/13 22:11
		(stepper of exposes of photoffenography)	EPO; JPO;	
			DERWENT;	
_	324	coater and developer and (stepper or expos\$5	IBM_TDB USPAT;	2004/07/14 12:24
	}	or lithography or photolithography) and	US-PGPUB;	2001/0//21 12:21
		maintenance	EPO; JPO;	
			DERWENT; IBM TDB	
-	3	'	USPAT;	2004/07/14 12:06
		expos\$5 or lithography or photolithography) and maintenance) and bottleneck	US-PGPUB;	
		and maintenance, and bottleneck	EPO; JPO; DERWENT;	
		(	IBM_TDB	000110=15
_	39	(coater and developer and (stepper or expos\$5 or lithography or photolithography)	USPAT; US-PGPUB;	2004/07/14 12:07
		and maintenance) and schedul\$5	EPO; JPO;	
			DERWENT;	
-	5460	(coater or developer or track) with	IBM_TDB   USPAT;	2004/07/14 12:34
		maintenance	US-PGPUB;	
			EPO; JPO;	
			DERWENT; IBM TDB	
-	16	((coater or developer or track) with	USPAT;	2004/07/14 12:26
		maintenance with schedul\$5) and (semiconductor or wafer or lithography or	US-PGPUB; EPO; JPO;	
		photolithography)	DERWENT;	
_	1323	(coater or developer) with maintenance	IBM_TDB USPAT;	2004/07/14 12:36
	1323	(codect of developer) with maintenance	US-PGPUB;	2004/07/14 12:36
			EPO; JPO;	
			DERWENT; IBM TDB	
-	161	((coater or developer) with maintenance) and	USPAT;	2004/07/14 13:07
		(semiconductor or wafer or photolithography or lithography)	US-PGPUB;	
		or remography,	EPO; JPO; DERWENT;	
	~ -	//acaban an danal-result	IBM_TDB	
-	31	((coater or developer) same maintenance same (schedul\$5 or perform\$5) same (expos\$5 or	USPAT; US-PGPUB;	2004/07/14 13:19
		stepper or photolithography or lithography))	EPO; JPO;	
			DERWENT; IBM TDB	
-	189	(coater or developer or track) with	USPAT;	2004/07/14 16:43
		maintenance with schedul\$5	US-PGPUB;	
			EPO; JPO; DERWENT;	
			IBM_TDB	
-	140	<pre>(expos\$5 with longer with (coat\$5 or develop\$)) and maintenance</pre>	USPAT;	2004/07/14 16:45
		develops; ) and maintenance	US-PGPUB; EPO; JPO;	
			DERWENT;	
-	132	700/99-103,121;702/177,184.ccls. and	IBM_TDB USPAT;	2004/10/25 17:17
]		@pd>=20040714	US-PGPUB;	2004/10/23 17:17
			EPO; JPO;	
			DERWENT; IBM TDB	
				<u> </u>